
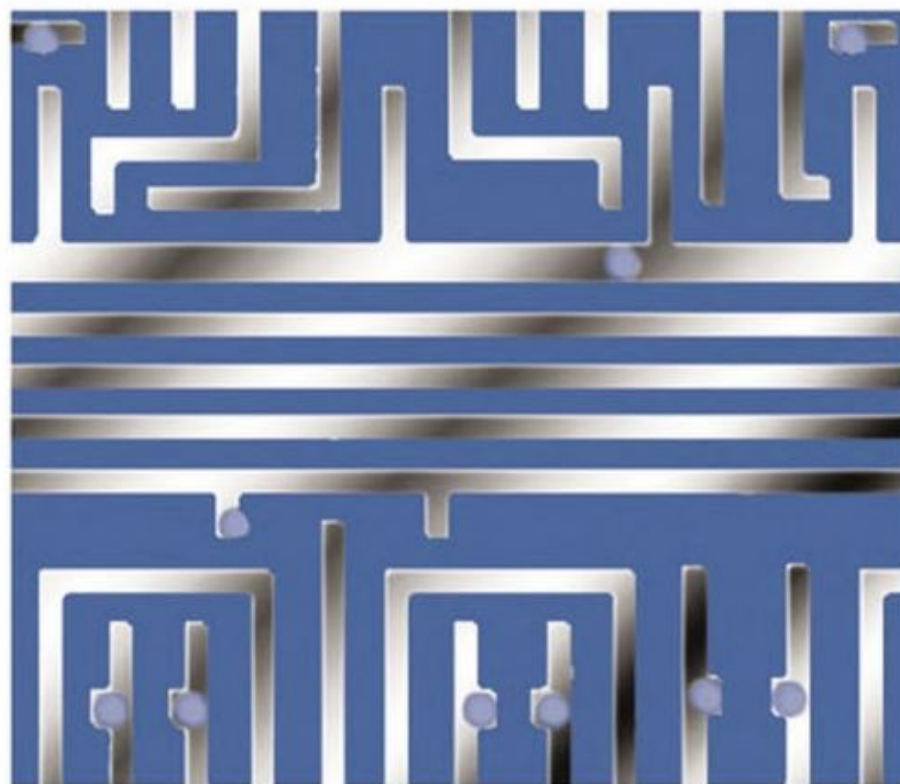


Joseph M. Steigerwald,
Shyam P. Murarka, Ronald J. Gutmann

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JOSEPH M. STEIGERWALD
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CONTENTS

Preface	xi
1 Chemical Mechanical Planarization—An Introduction	1
1.1 Introduction	1
1.2 Applications	4
1.3 The CMP Process	7
1.4 CMP Tools	10
1.5 Process Integration	11
1.6 Conclusion and Book Outline	11
References	13
2 Historical Motivations for CMP	15
2.1 Advanced Metallization Schemes	16
2.1.1 Interconnect Delay Impact on Performance	16
2.1.2 Methods of Reducing Interconnect Delay	19
2.1.3 Planarity Requirements for Multilevel Metallization	22
2.2 Planarization Schemes	25

v

vi CONTENTS

2.2.1 Smoothing and Global Planarization	
2.2.2 Global Planarization	
2.3 CMP Planarization	
2.3.1 Advantages of CMP	
2.3.2 Disadvantages of CMP	
2.3.3 The Challenge of CMP	
References	
3 CMP Variables and Manipulation	
3.1 Output Variables	
3.2 Input Variables	
References	
4 Mechanical and Electrochemical Aspects of CMP	
4.1 Preston Equation	
4.2 Fluid Layer Interactions	
4.3 Boundary Layer Interactions	
4.3.1 Fluid Boundary Layer	
4.3.2 Double Layer	
4.3.3 Metal Surface	
4.3.4 Mechanical Aspects	
4.4 Abrasion Modes	
4.4.1 Polishing vs. Abrasion	
4.4.2 Hertzian Indentation	
4.5 The Polishing Pad	
4.5.1 Pad Materials	
4.5.2 Pad Conditioning	
4.6 Electrochemical Phenomena	
4.6.1 Reduction-Oxidation	
4.6.2 Pourbaix Diagrams	
4.6.3 Mixed Potential	
4.6.4 Example: Copper	
4.6.5 Example: Copper	
4.7 Role of Chemistry in CMP	

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